



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masaaki KURIHARA et al.

Group Art Unit: 1756

Application No.: 10/614,345

Examiner: J. RUGGLES

Filed: July 8, 2003

Docket No.: 123770

For: PHASE MASK FOR FORMING DIFFRACTION GRATING, METHOD OF FABRICATING PHASE MASK AND METHOD OF FORMING DIFFRACTION GRATING

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the November 30, 2006 Office Action, the shortened statutory period for reply having been extended by the attached Petition for Extension of Time, please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**